Operation of a Small Pulsed Mevva an ECR Ion Source Environment, A. VASSILIEV, ITEP; and M. CAVENAGO, INFN LNL - The insertion of a small mevva ion source inside an ECR source is a promising way to inject metal atoms inside the ECR source, and to study plasma nonstationary regimes. The status of Nanomevva 1 and 2 is reported, giving performance of Nanomevva 1 with aluminium and lead cathodes. Insertion of Nanomevva 2 into the ECR source Alice is described, and details of the second power supply are discussed: it features remote control with fibre optic lines and with insulated mechanically operated Experimental programs include the switches. measurement of the Nanomevva output transmitted to the ECR Faraday cups and of the metal ion yield of ECR Alice during and after the Nanomevva operation.